

MPI TS200 | 200 mm Manual Probe System

For accurate and reliable DC/CV and RF measurements

Microscope Mount and Movement

- Stable bridge for high quality optics
- Linear Z lift for easy reconfiguration
- 25 x 25 mm air bearing or 50 x 50 mm linear XY movement

Adjustable Platen Height

- Micrometer control for precise adjustment
- 20 mm range for various applications

Probe Platen

- Stable and rigid design
- Supports DC/CV and RF measurements
- Rectangular adjustments for RF positioners
- Designed for maximum thermal stability

Unique Platen Lift

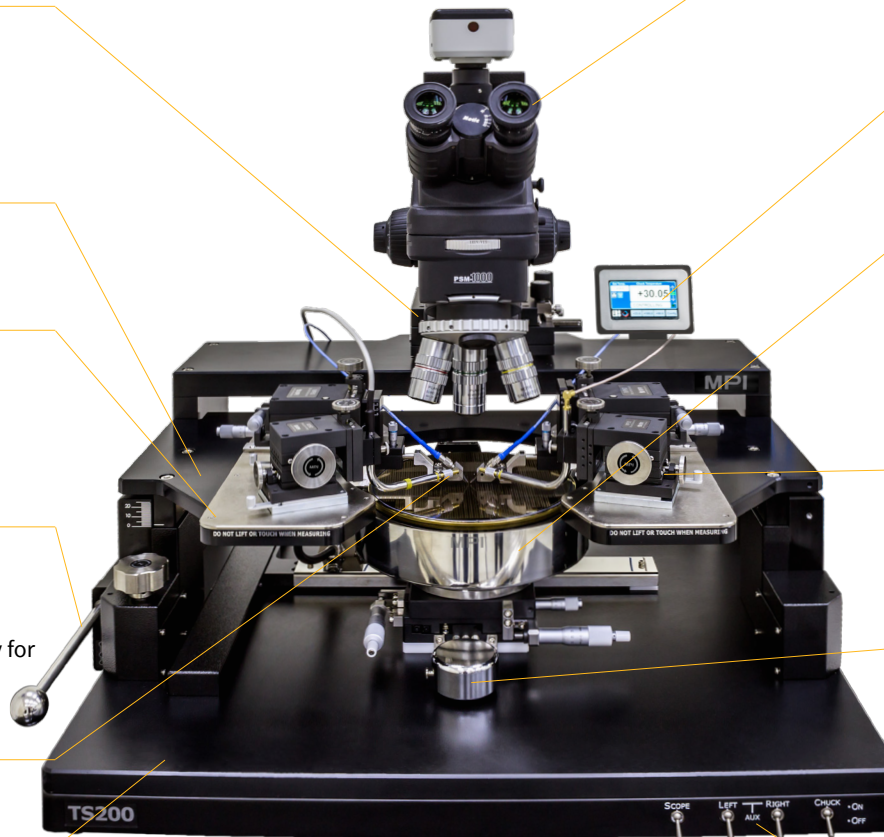
- Three discrete positions for contact, separation (300 μ m) and safety loading (3 mm)
- Safety lock function at loading position
- "Auto Contact" position with ± 1 μ m repeatability for consistent contact quality

RF Calibration

- 2 auxiliary chucks for calibration substrates
- Built-in ceramic for accurate calibration
- 1 μ m flatness for consistent contact quality

Small Footprint

- Designed for bench top use
- Comes with vibration absorber base
- Low profile design for maximum usability



Microscope and Optics Options

- Various optics options available
- Stereo MPI ST45 or single tube MPI SZ10, MZ12 with up to 12x zoom and 95 mm working distance
- High Power microscopes FS70/PSM-1000
- HDMI cameras, monitor user interface without computer

Thermal Chuck Integration

- Seamless integration of the thermal controller touch screen panel provides most convenient operation

Modular Chucks

- Various non-thermal or thermal chucks
- Choice of Triaxial or Coaxial connection
- Wide range of temperature up to 300 °C
- Field upgradable for reduced cost of ownership
- Easy switch between center and small wafer size control

DC and RF Positioners

- Supports up to 4 RF and 10 DC positioners
- Wide range of positioners available
- Dedicated probe arms for DC/CV and RF measurements

Chuck XY-Theta Stage Movement

- Unique puck controlled air bearing stage for quick single-handed operation
- 240 x 315 mm XY total stage movement
- Including 25 x 25 mm fine micrometer control
- Resolution < 1.0 μ m (0.04 mils) @ 500 μ m/rev
- Extra wide Y-range for easy loading
- $\pm 5^\circ$ Theta fine adjustment

Front Mounted Vacuum Control

- Easy access
- Clearly marked

Available Options

- Vibration isolation platform
- EMI-shielded DarkBox
- Vacuum pump and air compressor unit
- Table with integrated rack for thermal controller, computer and keyboard push tray
- Dual monitor stand option & Instrument shelf option